

PTO-1449 Information Disclosure Citation In an Application		Application No. Unknown 10/615,048	Applicant(s) James W. Blatchford, Jr., et al.
		Docket Number TI-35516 (032350.B504)	Group Art Unit Unknown 2825
Filing Date July 8, 2003			

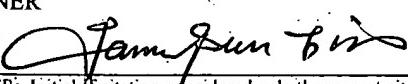
U.S. PATENT DOCUMENTS

		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A						
	B						
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FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	K							
	L							
	M							
	N							

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
O	FringeSoft, Zernike and Seidel Polynomials, Zernike polynomials, http://www.fringesoft.com/siedel.htm ; copyright 2000 FringeSoft; 2 pages.	June 28, 2000
P	Gennari, Frank E., "Validation of the aberration pattern-matching OPC strategy," Design, Process Integration, and Characterization for Microelectronics, Alexander Starikov, Kenneth W. Tobin, Jr., Editors, Proceedings of SPIE Vol. 4692, pages 444-453.	2002
Q	Calibre OPC and PSM, Manufacturability Datasheet, "Calibre OPC and PSM: Enabling Silicon Accuracy, Speed and Yield from 180nm to 65nm," Mentor Graphics, Mentor Graphics Corporation, www.mentor.com/dsm , 6 pages.	April 2003

EXAMINER	DATE CONSIDERED
	11-03-04

EXAMINER: Initial & citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.